Ellipsometry Advanced Modeling Techniques

Reference
ELL2

Price per attendee
For 2 days 1 210€
For 3 days 1 815€

Duration
2 days + 1 day optional

Dates
3-5 April and 16-18 October 2024

Registration deadline
3 March and 16 September 2024

Location
14 Boulevard Thomas Gobert,
91120 Palaiseau - France

Prerequisites
Dedicated to HORIBA customers only and knowledge of the technique and equipment.

Who should attend
Users of HORIBA Scientific Ellipsometry spectrometers and advanced users. A level of knowledge equivalent to Level ELL1 is required.

Certification
A diploma is delivered at the end of the course.

Learning method
Theoretical presentation and instruments practice.

Course language
English

Objectives

- This training course target advanced users, with a level of knowledge equivalent to ELL1. Attendees should have at least some ellipsometry experience and skill with DeltaPsi2 software.
- Provides a good practice of modeling methods used for the characterization of complex structures such as: unknown materials, ultra thin films, anisotropic samples, limited backside reflection parameterization, etc. Customers are invited to bring samples
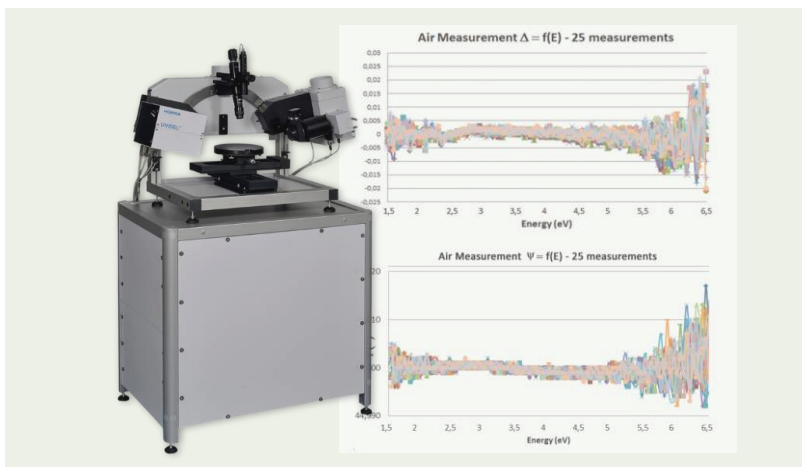
PROGRAM

Day 1

Practical Session of Non-ideal Samples: Measurements and Modelling:
· Review of theory
· Analysis of gradient layer
· Analysis of thick films >2μm
· Non-uniform thicknesses
· Study of depolarizing sample

Day 2

Practical Session of Non-ideal Samples:
· Analysis of combined ellipsometric and transmission data for thin metallic films sample
· Anisotropy: learn how to identify the axis orientation to run appropriate measurements for modelling
· Instrument calibration and troubleshooting

Day 3 (optional)

Practical Session with Customer Samples